

Docket No.: EHF 2001,0167 R



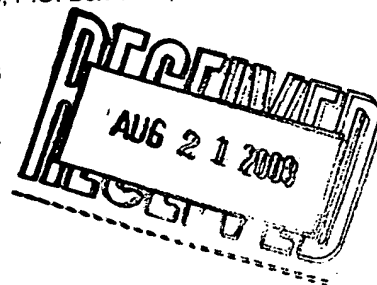
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I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as First Class Mail in an envelope addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on the date indicated below.

By: 

Date: August 15, 2003

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



Applicant : Norbert Benesch et al.  
Applic. No. : 09/873,230  
Filed : June 4, 2001  
Title : Method and Device for Optically Monitoring Fabrication  
Processes of Finely Structured Surfaces in a Semiconductor  
Production  
Art Unit : 2621

**RECEIVED**

AUG 20 2003

INFORMATION DISCLOSURE STATEMENT

Technology Center 2600

Hon. Commissioner for Patents

Sir:

In accordance with 37 C.F.R. 1.98 copies of the following patents and/or publications are submitted herewith:

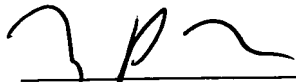
Japanese Patent Abstract JP 60 224 041 (Nakanishi et al.), dated November 8, 1985;

Korean Office Action dated June 23, 2003.

In accordance with 37 C.F.R. 1.97(e) the undersigned herewith states that each item of information contained in the information disclosure statement was first cited in a

communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of the information disclosure statement.

Respectfully submitted,



For Applicants

Mark P. Weichselbaum  
Reg. No. 43,248

Date: August 15, 2003

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